

ABSTRACT OF THE DISCLOSURE

5 Provided herein is a lid assembly for chemical vapor
deposition (CVD) process chamber, comprising a moveable lid, two
linear guide rollers connected to the lid, one or more linear lifting
actuators, and a rotation actuator connected to the axis of the lid.
This lid assembly may be used for opening/closing process chamber
as well as wet-cleaning process chamber in chemical vapor
10 deposition.

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